



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **WATANABE, et al.**

Group Art Unit: **2825**

Serial No.: **09/320,271**

Examiner: **Calvin Lee**

Filed: **May 27, 1999**

P.T.O. Confirmation No.: 4409

For: **SEMICONDUCTOR DEVICE AND FABRICATION METHOD THEREOF**

AMENDMENT AFTER FINAL REJECTION

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 14, 2004

Sir:

In response to the Office Action dated **October 17, 2003**, please amend the above-identified application as follows:

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